

Title (en)
Safety system for high vacuum system

Title (de)
Schutzvorrichtung für Hochvakuum pumpen

Title (fr)
Système de sécurité pour pompe à vide poussé

Publication
EP 2246573 A3 20111207 (DE)

Application
EP 10161376 A 20100428

Priority
CH 6682009 A 20090428

Abstract (en)
[origin: EP2246573A2] The device (11) has two connection flanges (15, 17) connected with each other by a pipe section defining a passageway (21). A third connection flange (20) is provided between the first and second connection flanges in the passageway. Baffle plates (23) are arranged at a certain distance from each other. The baffle plates are arranged in an expanded cross-sectional area (33) of the pipe section, and are arranged at a distance from the third connection flange. The cross-sectional area is provided with the pipe section for receiving the baffle plates. An independent claim is also included for a method for protecting a high vacuum pump from condensable vapors.

IPC 8 full level
F04B 37/08 (2006.01); **F04D 19/04** (2006.01); **F04D 27/02** (2006.01); **F04D 29/42** (2006.01)

CPC (source: EP)
F04B 37/08 (2013.01); **F04D 19/042** (2013.01); **F04D 27/0292** (2013.01); **F04D 29/4206** (2013.01)

Citation (search report)

- [X] US 6368371 B1 20020409 - NOMURA NORIHIKO [JP], et al
- [X] JP S58106186 A 19830624 - HITACHI LTD
- [A] US 5537833 A 19960723 - MATTE STEPHEN R [US], et al
- [A] US 6309184 B1 20011030 - MORAJA MARCO [IT], et al

Cited by
EP3019747A4; DE102011100311A1; DE102011100311A8; EP2520810A3; WO2015003651A1; US11655809B2

Designated contracting state (EPC)
AT BE BG CH CY CZ DE DK EE ES FI FR GB GR HR HU IE IS IT LI LT LU LV MC MK MT NL NO PL PT RO SE SI SK SM TR

Designated extension state (EPC)
AL BA ME RS

DOCDB simple family (publication)
EP 2246573 A2 20101103; EP 2246573 A3 20111207; EP 2246573 B1 20130213

DOCDB simple family (application)
EP 10161376 A 20100428